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Correction: An elastomer for epidermal electronics with adjustable adhesion force and stretchability obtained *via* a reverse-micelle-induced process

Junhyung Kim,^{ab} Yujin Hwang,^{ab} Sunho Jeong,^a Su Yeon Lee,^a Youngmin Choi^{*ab} and Sungmook Jung^{*a}

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The Royal Society of Chemistry apologises for these errors and any consequent inconvenience to authors and readers.

^a Division of Advanced Materials, Korea Research Institute of Chemical Technology (KRICT), 141 Gajeongro, Daejeon 305-600, Republic of Korea.

E-mail: mooktank@kRICT.re.kr

^b Department of Chemical Convergence Materials, Korea University of Science and Technology (UST), 217 Gajeongro, Yuseong-gu, Daejeon 305-350, Korea

